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APPLICATION NO.	FI	LING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO	
09/532,022	(03/21/2000	Yuji Sudoh	35.G2558		
5514	7590	10/08/2002		_		
		LA HARPER &	EXAMINER			
30 ROCKE NEW YOR				NGUYEN, HUNG		
				ART UNIT	PAPER NUMBER	
				2851		
			DATE MAILED: 10/08/2002			

Please find below and/or attached an Office communication concerning this application or proceeding.

	1								
_ •		Application No.	Applicant(s)						
Office Action Summary		09/532,022	SUDOH ET AL.						
		Examiner	Art Unit						
		Hung Henry V Nguyen	2851						
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply									
A SHORTENED STATUTOR THE MAILING DATE OF TH - Extensions of time may be available after SIX (6) MONTHS from the mail - If the period for reply specified above - If NO period for reply is specified above - Failure to reply within the set or exter - Any reply received by the Office later earned patent term adjustment. See Status	IIS COMMUNICATION. under the provisions of 37 CFR 1.1: ng date of this communication. is less than thirty (30) days, a reply ve, the maximum statutory period v ided period for reply will, by statute than three months after the mailing	36(a). In no event, however, may a within the statutory minimum of thi vill apply and will expire SIX (6) MOI cause the application to become A	reply be timely filed rly (30) days will be considered time NTHS from the mailing date of this of BANDONED (35 U.S.C. § 133).						
1) Responsive to comm	unication(s) filed on <u>C.P</u>	.A.filed 9/10/02 .							
2a)☐ This action is FINAL	. 2b)⊠ Th	is action is non-final.							
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.									
Disposition of Claims	s with the practice under	Ex parte Quayle, 1955 C	.D. 11, 4 55 O.G. 215.						
4)⊠ Cłaim(s) <u>25-48</u> is/are	pending in the application	n.							
4a) Of the above clain	n(s) is/are withdraw	wn from consideration.							
5) Claim(s) is/are	allowed.								
6)⊠ Claim(s) <u>25-48</u> is/are rejected.									
7) Claim(s) is/are	objected to.								
• • • — —	bject to restriction and/o	r election requirement.							
Application Papers									
9) The specification is objected to by the Examiner.									
10)⊠ The drawing(s) filed on <u>21 <i>March 2000</i></u> is/are: a)⊠ accepted or b)□ objected to by the Examiner.									
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).									
11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.									
If approved, corrected drawings are required in reply to this Office action.									
12) The oath or declaration is objected to by the Examiner.									
Priority under 35 U.S.C. §§ 11			0.440(.) (1) (0						
13)⊠ Acknowledgment is m	,	n prionty under 35 U.S.C.	§ 119(a)-(d) or (f).						
a)⊠ All b)□ Some * c									
	of the priority document								
<u> </u>		s have been received in A		_					
 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 									
14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).									
a) ☐ The translation of 15)☐ Acknowledgment is ma		visional application has t							
Attachment(s)		- •							
Notice of References Cited (PTC 2) Notice of Draftsperson's Patent D Information Disclosure Statemen	rawing Review (PTO-948)	5) Notice of	Summary (PTO-413) Paper No Informal Patent Application (PT						

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DETAILED ACTION

Continued Prosecution Application

1. The request filed on September 10, 2002 for a Continued Prosecution Application (CPA) under 37 CFR 1.53(d) based on parent Application No. 09/532,022 is acceptable and a CPA has been established. An action on the CPA follows.

Claim Rejections - 35 USC § 112

- 2. The following is a quotation of the first paragraph of 35 U.S.C. 112:
 - The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.
- 3. Claims 25-48 are rejected under 35 U.S.C. 112, first paragraph, as containing subject matter which was not described in the specification in such a way as to reasonably convey to one skilled in the relevant art that the inventor(s), at the time the application was filed, had possession of the claimed invention. The disclosure of the specification lacks adaquate support for the claimed provision of "projection optical system including a diaphragm arranged in a vacuum" (see claim 1 for example). In response to the Final Rejection made March 12, 2002, Applicant cancelled claims 1-24 and added new independent claims 25 and 37 that recite limitation of "projection optical system including a diaphragm arranged in a vacuum". The applicants stated that support for newly added claims can be found in the specification as filed and directed the Examiner's attention to the specification beginning at page 7, line 9 and particularly page 12, lines 13-20. However, the Examiner was unable to find the claimed limitations as mentioned in the specification except for an ambiguous statement stating "the"

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present invention is applied to an exposure optical system used in the atmosphere, the present is also applicational to an exposure apparatus using EUV or X-rays. In that case, the present invention is more effective, because exposure is performed in vacuum, and a natureal radiation effect is reduced more, as compared with a case in which exposure is performed in the atmostphere" (see present specification, page 12, lines 13-20). This paragraph is not even remotely related to the limitations as recited in the instant independent claims 25 and 37. The applicant is remined that when claimed elements that are not clearly discussed in detail, this falls under 112, first paragraph, applicant's disclosure is lacking in this aspect and for this reason, one having ordinary skill in the art is unable to ascertain the particularities and the highlights of applicant's claimed invention.

- 4. The following is a quotation of the second paragraph of 35 U.S.C. 112:
 The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.
- 5. Claims 25-48 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

As to claims 25 and 37, the recitation of "of "projection optical system including a diaphragm arranged in a vacuum" is vague and indefinite for the above reasons (see rejection under 35 U.S.C. 112, first paragraph".

Claim Rejections - 35 USC § 103

1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

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(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

2. Claims 24-48 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ushida et al (U.S.Pat. 5,530,518) in view of Shiraishi (U.S.Pat. 6,020,950) and further in view of Sato (U.S.Pat. 5,142,148)

With regard to claims 24-48 Ushida et al (fig. 1) discloses an projection exposure apparatus comprising: a projection optical system (10) for projection a pattern formed on a reticle (9) onto a photosensitive substrate (11) and a diaphragm (10a) for setting the numerical aperture of the projection optical system. Ushida lacks to show a mechanism for controlling the temperature of the diaphragm. Shiraishi (figs 4 and 5) teaches a projection optical system having a cooling member (see fig. 5) for cooling the light shielding plate arranged therein whereby "the system is free from heat generation caused by light absorption" (see col.5, lines 15-18) wherein the cooling means comprises a cooling fluid circulation system (Ko,Ki). Ushida as mofied by Shiraishi does not expressly disclose the diaphram arranged in vacuum. Sato discloses an exposure apparatus where the aperture diaphragm is disposed in a vacuum for preventing from being contaminated (see col.2, lines 3-16). It would have been obvious to one having ordinary skill in the art at the time the invention was made to combine the teachings of Ushida, Shiraishi and Sato to obtain the claimed invention.

With respect to claims 31 and 43, it is noted that the temperature of fluid is controlled (see col.14, lines 5-7). Therefore, a temperature sensor is an inherent device of the cooling means to detect the temperature information of the light shielding plate.

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As to claims 32-33, and 44-45, it is the examiner's position that it would have been obvious to a skilled artisan to preferably disposed the temperature sensor on the side facing the substrate. In other words, the sensor is disposed on a plane opposite to the light source whereby the sensor is not influenced by the exposure beam.

It would have been obvious to one having ordinary skill in the art at the time the invention was made to combine the teachings of Ushida et al and Shiraishi et al to obtain the invention as specified in claims 24-48 of the instant invention. It would have been obvious to a skilled artisan to utilize the cooling means as taught by Shiraishi into the diaphragm of Ushida so that the numerical aperture diaphragm may be prevented from increasing its temperature due to absorption of light and thus a deviation of the projection optical system can be avoided and to place the diaphragm in a vacuum as suggested by Sato so that the diaphragm is prevented from damage caused by contamination.

3. Claims 34-35 and 46-47 are rejected under 35 U.S.C. 103(a) as being unpatentable over Ushida et al (U.S.Pat. 5,530,518) in view of Shiraishi (U.S.Pat. 6,020,950) and further in view of Sato and further in view of Nishi et al (U.S.Pat. 5,894,341).

As to claims 34-35, and 46-47, Ushida et al as modified by Shiraishi and Sato comprising substantially of the limitations of the instant invention as discussed above except for the aperture diaphragm comprises an iris diaphragm and a turret having a plurality of openings. However, a variable aperture of a turret type is known per se. For instance, Nishi teaches an aperture comprising "iris diaphragm and a turret with a plurality of openings". (see figs.2a, 2b). It would have been obvious to one having ordinary skill in the art at the time the invention was made to

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employ a variable aperture of a turret type as taught by Nishi in the device of Ushida as modified by Shiraishi and Sato for varying the numerical aperture of the projection optical system.

As to claims 30 and 42, Ushida et al as modified by Shiraishi and Sato lacks to show a cooling device with a "Peltier element". Using a "Peltier element" in a cooling mechanism is also well known in the art. For example, Nishi teaches Peltier element (30) for cooling the bottom face of the temperature adjustment plate (20). It would have been obvious to one having ordinary skill in the art at the time the invention was made to employ "Peltier element" as taught by Nishi into the cooling device of Shiraishi for the purpose of cooling the aperture stop and thus the aperture stop can be prevented from increasing its temperature due to absorption of light.

Response to Amendment

4. Applicant's arguments filed August 12, 2002 have been carefully reviewed but have been traversed in view of new grounds of rejection as set forth above.

Prior Art Made of Record

5. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

Takahashi (U.S.Pat. 6,023,068) and Ota (U.S.Pat. 6,359,678) discloses an exposure apparatus having aperture disposed in vacuum.

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6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Henry Hung V Nguyen whose telephone number is 703-305-6462. The examiner can normally be reached on Monday-Friday (First Friday off).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Russ Adams can be reached on 703-308-2847. The fax phone numbers for the organization where this application or proceeding is assigned are 703-305-7723 for regular communications and 703-305-7723 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-305-4900.

enry Hung V Nguyen

Examiner
Art Unit 2851

hvn October 6, 2002